



812
IFW

PTO/SB/21 (09-04)
Approved for use through 07/31/2006. OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE
Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number.

TRANSMITTAL FORM

(to be used for all correspondence after initial filing)

Total Number of Pages in This Submission

12

Application Number

10/518,345

Filing Date

December 17, 2004

First Named Inventor

Yoko Watanabe

Art Unit

2812

Examiner Name

Kaya L. Lewis Baltimore

Attorney Docket Number

075834.00404

ENCLOSURES (Check all that apply)

☐

Fee Transmittal Form

☐

Fee Attached

☐

Amendment/Reply

☐

After Final

☐

Affidavits/declaration(s)

☐

Extension of Time Request

☐

Express Abandonment Request

☐

Information Disclosure Statement

☐

Certified Copy of Priority Document(s)

☐

Reply to Missing Parts/
Incomplete Application

☐

Reply to Missing Parts
under 37 CFR 1.52 or 1.53

☐

Drawing(s)

☐

Licensing-related Papers

☐

Petition

☐

Petition to Convert to a
Provisional Application

☐

Power of Attorney, Revocation

☐

Change of Correspondence Address

☐

Terminal Disclaimer

☐

Request for Refund

☐

CD, Number of CD(s) _____

☐

Landscape Table on CD

☐

After Allowance Communication to TC

☐

Appeal Communication to Board
of Appeals and Interferences

☐

Appeal Communication to TC
(Appeal Notice, Brief, Reply Brief)

☐

Proprietary Information

☐

Status Letter

☒

Other Enclosure(s) (please identify
below):

Request for corrected filing receipt
with supporting documents
Post card

Remarks

The Commissioner is hereby authorized to charge any fees due or to credit any overpayment to
Deposit Account No. 20-1495

SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm Name

Trexler, Bushnell, Giangorgi, Blackstone & Marr, Ltd.
105 West Adams Street, Suite 3600, Chicago, IL 60603-6299

Signature

Printed name

Lewis T. Steadman

Date

September 28, 2005

Reg. No.

17, 074

CERTIFICATE OF TRANSMISSION/MAILING

I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date shown below:

Signature

Typed or printed name

Lewis T. Steadman

Date

9-28-05

This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.11 and 1.14. This collection is estimated to 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No.: 10/518,345 **Confirmation No.:** 5254

Applicants: Yoko Watanabe et al.

Filed: December 17, 2004

TC/A.U.: 2812

Title: **MASK, METHOD OF INSPECTING THE SAME, AND
METHOD OF PRODUCING SEMICONDUCTOR DEVICE**

Examiner: Kaya L. Lewis Baltimore

Docket No.: 075834.00404

Customer No.: 33448

REQUEST FOR CORRECTED FILING RECEIPT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313

Sir:

Attached is a copy of the Filing Receipt received in the above-identified application.

This Filing Receipt is incorrect in that it omits the name of the fourth inventor:

Keiko Amai, Kanagawa, Japan

Applicants have attached a copy of the executed Declaration, evidencing the inventors named in this application.

The Filing Receipt is further incorrect in that the title of the invention should be listed as:

**MASK, METHOD OF INSPECTING THE SAME,
AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE**

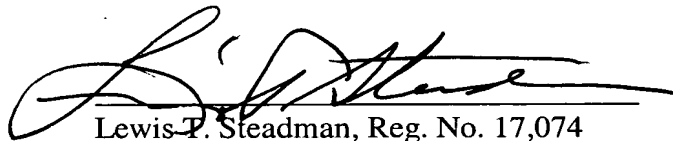
Applicant has attached a copy of the Preliminary Amendment Accompanying the Filing of this application and of the first page of the English language translation, modifying the title to match that of the English language translation.

Accordingly, we respectfully request that the we receive an updated Filing Receipt reflecting the corrections listed above.

It is believed that no fee is required, however, if the Commissioner believes otherwise, the Commissioner is hereby authorized to charge the fees to Deposit Account No. 20-1495.

Respectfully submitted,

Sept 28, 2005



Lewis T. Steadman, Reg. No. 17,074

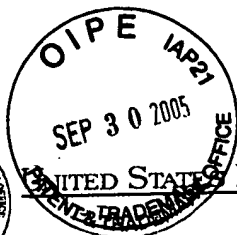
**Trexler, Bushnell, Giangiorgi,
Blackstone & Marr, Ltd.**

105 W. Adams, 36th Floor

Chicago, Illinois 60603

Tel: (312) 704-1890

Attorneys for Applicant



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
 United States Patent and Trademark Office
 Address: COMMISSIONER FOR PATENTS
 P.O. Box 1450
 Alexandria, Virginia 22313-1450
 www.uspto.gov

APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/518,345	12/17/2004	2812	1300	075834.00404	13	28	3

CONFIRMATION NO. 5254

33448

ROBERT J. DEPKE

LEWIS T. STEADMAN

TREXLER, BUSHNELL, GLANGLORGI, BLACKSTONE & MAHH, LTD.

105 WEST ADAMS STREET, SUITE 3600

CHICAGO, IL 60603-6299

ANNOTATED

FILING RECEIPT



CC000000016991891*

SEP 26 2005

Date Mailed: 09/20/2005

TREXLER, BUSHNELL, GIANGIORGI,
 BLACKSTONE & MAHH, LTD.

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please mail to the Commissioner for Patents P.O. Box 1450 Alexandria Va 22313-1450. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Yoko Watanabe, Tokyo, JAPAN;

Shinji Omori, Kanagawa, JAPAN;

Kazuya Iwase, Kanagawa, JAPAN;

Masaki Yoshizawa, Kanagawa, JAPAN;

Keiko Amai, Kanagawa, JAPAN

Power of Attorney: The patent practitioners associated with Customer Number 33448.

Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP03/08176 06/27/2003

Foreign Applications

JAPAN 2002-191099 06/28/2002

JAPAN 2003-129523 05/07/2003

Projected Publication Date: 12/22/2005**Non-Publication Request:** No**Early Publication Request:** No

Title

~~Mask and inspection method therefor and production method for semiconductor device~~
 MASK, METHOD OF INSPECTING THE SAME, AND METHOD OF PRODUCING
 SEMICONDUCTOR DEVICE

Preliminary Class

438

PROTECTING YOUR INVENTION OUTSIDE THE UNITED STATES

Since the rights granted by a U.S. patent extend only throughout the territory of the United States and have no effect in a foreign country, an inventor who wishes patent protection in another country must apply for a patent in a specific country or in regional patent offices. Applicants may wish to consider the filing of an international application under the Patent Cooperation Treaty (PCT). An international (PCT) application generally has the same effect as a regular national patent application in each PCT-member country. The PCT process **simplifies** the filing of patent applications on the same invention in member countries, but **does not result** in a grant of "an international patent" and does not eliminate the need of applicants to file additional documents and fees in countries where patent protection is desired.

Almost every country has its own patent law, and a person desiring a patent in a particular country must make an application for patent in that country in accordance with its particular laws. Since the laws of many countries differ in various respects from the patent law of the United States, applicants are advised to seek guidance from specific foreign countries to ensure that patent rights are not lost prematurely.

Applicants also are advised that in the case of inventions made in the United States, the Director of the USPTO must issue a license before applicants can apply for a patent in a foreign country. The filing of a U.S. patent application serves as a request for a foreign filing license. The application's filing receipt contains further information and guidance as to the status of applicant's license for foreign filing.

Applicants may wish to consult the USPTO booklet, "General Information Concerning Patents" (specifically, the section entitled "Treaties and Foreign Patents") for more information on timeframes and deadlines for filing foreign patent applications. The guide is available either by contacting the USPTO Contact Center at 800-786-9199, or it can be viewed on the USPTO website at <http://www.uspto.gov/web/offices/pac/doc/general/index.html>.

For information on preventing theft of your intellectual property (patents, trademarks and copyrights), you may wish to consult the U.S. Government website, <http://www.stopfakes.gov>. Part of a Department of Commerce initiative, this website includes self-help "toolkits" giving innovators guidance on how to protect intellectual property in specific countries such as China, Korea and Mexico. For questions regarding patent enforcement issues, applicants may call the U.S. Government hotline at 1-866-999-HALT (1-866-999-4158).

LICENSE FOR FOREIGN FILING UNDER

Title 35, United States Code, Section 184

Title 37, Code of Federal Regulations, 5.11 & 5.15

GRANTED

The applicant has been granted a license under 35 U.S.C. 184, if the phrase "IF REQUIRED, FOREIGN FILING LICENSE GRANTED" followed by a date appears on this form. Such licenses are issued in all applications where the conditions for issuance of a license have been met, regardless of whether or not a license may be required as set forth in 37 CFR 5.15. The scope and limitations of this license are set forth in 37 CFR 5.15(a) unless an earlier license has been issued under 37 CFR 5.15(b). The license is subject to revocation upon written notification. The date indicated is the effective date of the license, unless an earlier license of similar scope has been granted under 37 CFR 5.13 or 5.14.

This license is to be retained by the licensee and may be used at any time on or after the effective date thereof unless it is revoked. This license is automatically transferred to any related applications(s) filed under 37 CFR 1.53(d). This license is not retroactive.

The grant of a license does not in any way lessen the responsibility of a licensee for the security of the subject matter as imposed by any Government contract or the provisions of existing laws relating to espionage and the national security or the export of technical data. Licensees should apprise themselves of current regulations especially with respect to certain countries, of other agencies, particularly the Office of Defense Trade Controls, Department of State (with respect to Arms, Munitions and Implements of War (22 CFR 121-128)); the Bureau of Industry and Security, Department of Commerce (15 CFR parts 730-774); the Office of Foreign Assets Control, Department of Treasury (31 CFR Parts 500+) and the Department of Energy.

NOT GRANTED

No license under 35 U.S.C. 184 has been granted at this time, if the phrase "IF REQUIRED, FOREIGN FILING LICENSE GRANTED" DOES NOT appear on this form. Applicant may still petition for a license under 37 CFR 5.12, if a license is desired before the expiration of 6 months from the filing date of the application. If 6 months has lapsed from the filing date of this application and the licensee has not received any indication of a secrecy order under 35 U.S.C. 181, the licensee may foreign file the application pursuant to 37 CFR 5.15(b).



- 1 -

COPY

MAIL STOP PCT
IN THE UNITED STATES ELECTED OFFICE
OF THE UNITED STATES PATENT AND TRADEMARK OFFICE
UNDER THE PATENT COOPERATION TREATY

PRELIMINARY AMENDMENT
ACCOMPANYING THE FILING OF AN APPLICATION

APPLICANT(s): Yoko Watanabe et al.
ATTORNEY DOCKET NO.: 075834.00404
INTERNATIONAL APPLICATION NO.: PCT/JP03/08176
INTERNATIONAL FILING DATE: June 27, 2003
INVENTION: MASK AND INSPECTION METHOD THEREFOR AND
PRODUCTION METHOD FOR SEMICONDUCTOR
DEVICE
CUSTOMER NO.: 33448

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

TITLE OF THE INVENTION

Please amend the title of the invention to:

~~MASK AND INSPECTION METHOD THEREFOR AND PRODUCTION
METHOD FOR SEMICONDUCTOR DEVICE~~

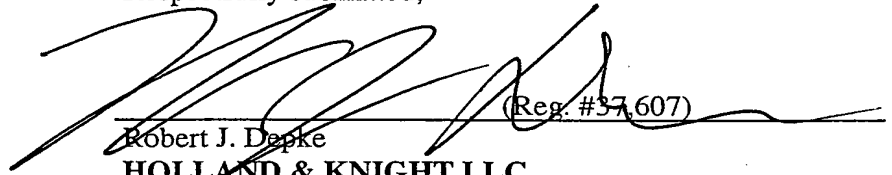
MASK, METHOD OF INSPECTING THE SAME, AND METHOD OF
PRODUCING SEMICONDUCTOR DEVICE

IN THE SPECIFICATION:

Before the first line insert:

--This application claims priority to Japanese Patent Application Number JP2002-191099, filed June 28, 2002, and Japanese Patent Application Number JP2003-129523, filed July 5, 2003 which are incorporated herein by reference.—

Respectfully submitted,

A large, stylized handwritten signature in black ink, appearing to read 'R. Depke', is written over a horizontal line. To the right of the signature, the text '(Reg. #37,607)' is printed.

Robert J. Depke

HOLLAND & KNIGHT LLC

131 South Dearborn Street, 30th Floor

Chicago, Illinois 60603

Tel: (312) 422-9050

Attorney for Applicants



DESCRIPTION

COPY

MASK, METHOD OF INSPECTING THE SAME, AND METHOD OF
PRODUCING SEMICONDUCTOR DEVICE

5

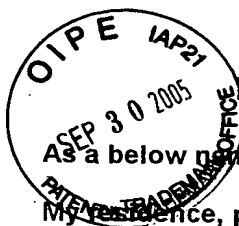
TECHNICAL FIELD

The present invention relates to a mask being used
at the lithography process in producing of a
semiconductor device, a method of inspecting the same,
10 and a method of producing the semiconductor device.

BACKGROUND ART

As an alternative exposing technology of a next
generation to photolithography, a printing type exposing
15 technology using a charge particle such as an electron
beam (strut) or an ion beam has being developed. In these
new technology mutually, the mask having a thin film
region, in other words a membrane, is used. The membrane
on the surface of the mask has the thickness of about 100
20 nm to 10 μm , a printing pattern is placed on the membrane.
The membrane is formed by etching a mask material, for
example containing a silicon wafer, in part from the
reverse side of the mask. A portion without etching of a
mask blanks becomes a supporting portion of the membrane.

25 The thing that the printing pattern is formed by



503706910000

DECLARATION AND POWER OF ATTORNEY

COPY

As a below named inventor, I hereby declare that:

My residence, post office address and citizenship are as stated below next to my name,

I believe I am the original, first and sole inventor (if only one name is listed below) or an original, first and joint inventor (if plural names are listed below) of the subject matter which is claimed and for which a patent is sought on the invention entitled:

MASK, METHOD OF INSPECTING THE SAME,
AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE

Case No. 075834.00404, the specification of which

(check one) ☒ is attached hereto.
was filed on June 27, 2003 as
Application Serial No. PCT/JP03/08176
and was amended on _____
(if applicable)

I hereby state that I have reviewed and understand the contents of the above identified specification, including the claims as amended by any amendment referred to above.

I acknowledge the duty to disclose to the United States Patent Office all information which is known to me to be material to the patentability of this application in accordance with Title 37, Code of Federal Regulations, 1.56.¹

I do not know and do not believe this invention was ever known or used in the United States of America before my or our invention thereof, or patented or described in any printed publication in any country before my or our invention thereof or more than one year prior to this application, that the same was not in public use or on sale in the United States of America more than one year prior to this application, and I believe that the invention has not been patented or made the subject of an inventor's certificate issued before the date of this application in any country foreign to the United States of America on an application filed by me or my legal representatives or assigns more than twelve months prior to this application, and that no application for patent or inventor's certificate on this invention has been filed in any country foreign to the United States of America prior to this application by me or my legal representatives or assigns, except as identified below:

I hereby claim foreign priority benefits under Title 35, United States Code, 119 of any foreign application(s) for patent or inventor's certificate listed below

Prior Foreign Application(s)

Number

Country

Date

2002-191099

Japan

June 28, 2002

2003-129523

Japan

May 7, 2003

PCT/JP03/08176

WO

June 27, 2003

and have also identified below any foreign application for patent or inventor's certificate having a filing date before that of the above listed application on which priority is claimed:

¹ (b) Under this section, information is material to patentability when it is not cumulative to information already of record or being made of record in the application, and

- (1) It establishes, by itself or in combination with other information, a *prima facie* case of unpatentability of a claim; or
(2) It refutes, or is inconsistent with, a position the applicant takes in:

- (i) Opposing an argument of unpatentability relied on by the Office, or
(ii) Asserting an argument of patentability.

A *prima facie* case of unpatentability is established when the information compels a conclusion that a claim is unpatentable under the preponderance of evidence, burden-of-proof standard, giving each term in the claim its broadest reasonable construction consistent with the specification, and before any consideration is given to evidence which may be submitted in an attempt to establish a contrary conclusion of patentability.

Prior Foreign Application(s)
Number Country Date

If no priority is claimed, I have identified all foreign patent applications filed prior to this application:

Prior Foreign Application(s)
Number Country Date

And I hereby appoint Lewis T. Steadman, Sr. (17,074), Robert J. Depke (37,607) and Todd S. Parkhurst (26,494), all members of the firm of Holland & Knight LLC

Telephone: (312) 263-3600

as my attorney with full power of substitution and revocation, to prosecute this application and to transact all business in the Patent and Trademark Office connected therewith and direct that all correspondence be forwarded to:

Holland & Knight LLC
131 South Dearborn, 30th Floor
Chicago, Illinois 60603

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

Full name of sole or first inventor Yoko WATANABE

Inventor's signature Yoko Watanabe Date October 14, 2004
Residence Kanagawa, Japan
Citizenship Japan
Post Office Address c/o Sony Corporation
7-35, Kitashinagawa 6-chome, Shinagawa-Ku, Tokyo 141-0001 JAPAN

Full name of second joint inventor,
(if any) Shinji OMORI

Inventor's signature Shinji Omori Date October 22, 2004
Residence Kanagawa, Japan
Citizenship Japan
Post Office Address c/o Sony Corporation
7-35, Kitashinagawa 6-chome, Shinagawa-Ku, Tokyo 141-0001 JAPAN

Full name of third joint inventor,
(if any) Kazuya IWASE

Inventor's signature Kazuya Iwase Date October 14, 2004
Residence Kanagawa, Japan
Citizenship Japan
Post Office Address c/o Sony Corporation
7-35, Kitashinagawa 6-chome, Shinagawa-Ku, Tokyo 141-0001 JAPAN


Full name of fourth joint inventor,
(if any) Keiko AMAI

Inventor's signature Keiko Amai Date October 15, 2004
Residence Kanagawa, Japan
Citizenship c/o Forum Engineering Inc.
Post Office Address 10-2, Naka-machi 4-chome, Atsugi-shi, Kanagawa 243-0018 JAPAN

Full name of fifth joint inventor,
(if any)

Masaki YOSHIZAWA

Inventor's signature



Date November 19, 2004

Residence

Kanagawa, Japan

Citizenship

Japan

Post Office Address

c/o Sony Corporation

7-35, Kitashinagawa 6-chome, Shinagawa-Ku, Tokyo 141-0001 JAPAN